

PLASUS EMICON SA Series

Data Sheet

	EMICON I SA – 8 SA			
Number of spectrometer channels	I - 8			
Spectral range	200 - 1100 nm (totally covered by each spectrometer)			
Number of wavelength channels (monitor tracks)	unlimited (selected by software without hardware modification)			
Analysis of monitor tracks	single, combined (+,-, /,*), ratio, average, integral			
Spectral resolution	1.5 nm FWHM			
Minimum time resolution	l ms			
Detector	CCD array with 16 Bit A/D converter			
Optical fiber connector	SMA 905			
Analog inputs	2 (4, 8) x 0-10 volts (iCoupler)			
Analog outputs	4 (8) x 0-10 volts (iCoupler)			
Digital outputs	8 (16) x TTL / 24V (Opto-Coupler)			
Digital inputs	8 (16) x TTL / 24V (Opto-Coupler)			
Remote control interfaces	Analog outputs, Digital IOs, Fieldbus, LAN API			
Processor unit	Integrated MPU with EMCON SA operation system			
Display	5,7" color touch panel (resistive)			
Power supply	5 VDC 4A			
Housing	19" rack mount box (4U, 84HP)			
Dimensions [mm]	480(w) x 190(h) x 420(d)			
Weight [kg]	3.5			
Remote software	EMICON SA Manager software on Windows® 7/8/10			
Windows computer requirements	Intel Core i5 / AMD Ryzen 5, 8 GB RAM, 256 GB SSD, LAN port, Windows® 7/8/10			
Typical applications	PECVD, (reactive) sputtering, etching, HIPIMS, ATM plasmas			
Field of application	process control, QA/QC, endpoint detection, fault detection in production lines			

Other options are available on request



PLASUS EMICON MC Series

Data Sheet

	EMICON I MC / 2 MC	EMICON 3 MC – 8 MC			
Number of spectrometer channels	I - 2	3 – 8			
Spectral range	200 - 1100 nm (totally covered by each spectrometer)				
Number of wavelength channels (monitor tracks)	unlimited (selected by software without hardware modification)				
Analysis of monitor tracks	single, combined (+,-, /,*), ratio, average, integral				
Spectral resolution	I.5 nm FWHM				
Minimum time resolution	approx. 15 ms				
Exposure time	I ms – 65 sec				
Detector	CCD array with 16 Bit A/D converter				
Optical fiber connector	SMA 905				
Analog outputs*	4 x ±10 volts	8 × ±10 volts			
Digital outputs*	2 x TTL	4 x TTL			
Digital inputs*	2 x TTL	4 x TTL			
Electrical connector*	BNC				
Remote control interfaces (optional)	Analog outputs, Digital IOs, LAN API				
PC connections	I x USB (USB-LAN-USB extension available)				
Power supply	5 VDC 2A	5 VDC 5A			
Housing	10" desktop box (3U, 42HP)	19" rack mount box (3U, 84HP)			
Dimensions [mm]	240 x 135 x 320	345 × 135 × 320			
Weight [kg]	2.5	3.5 – 4.5			
Software	EMICON multi-channel software				
Windows computer requirements	Intel Core i5 / AMD Ryzen 5, 8 GB RAM, 256 GB SSD, USB 2 port, Windows® 7/8/10				
Typical applications	PECVD, (reactive) sputtering, etching, HIPIMS, ATM plasmas				
Field of application	QA/QC, process control/development, endpoint detection, fault detection, plasma analysis				

^{*} Other options are available on request

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PLASUS EMICON HR Series

Data Sheet

	EMICON HR UV-VIS-NIR	EMICON HR UV	EMICON HR VIS	EMICON HR NIR		
Spectral range	200 - 860 nm	200 - 440 nm	440 – 670 nm	670 – 860 nm		
Number of spectrometer channels	ı					
Number of wavelength channels (monitor tracks)	unlimited (selected by software without hardware modification)					
Analysis of monitor tracks	single, combined (+,-, /,*), ratio, average, integral					
Spectral resolution	0.15 nm FWHM					
Time resolution	approx. 15 ms					
Exposure time	I ms – 65 sec					
A/D converter	l 6 Bit					
Optical fiber connector	SMA 905					
Analog outputs*	4 x ±10 volts					
Digital outputs*	2 × TTL					
Digital inputs*	2 x TTL					
Electrical connector*	BNC					
Remote control interfaces (optional)	Analog outputs, Digital IOs, LAN API					
PC connections	I x USB (USB-LAN-USB extension available)					
Power supply	5 VDC 5A					
Housing	I0" desktop box (3U, 42HP)					
Dimensions [mm]	240 × 135 × 320					
Weight [kg]	3.5					
Software	EMICON High-Resolution software					
Windows Computer requirements	Intel Core i5 / AMD Ryzen 5, 8 GB RAM, 256 GB SSD, USB 2 port, Windows® 7/8/10					
Typical applications	PECVD, (reactive) sputtering, etching, HIPIMS, ATM plasmas					
Field of application	R&D, plasma analysis, process development/optimization/control, endpoint detection, QA/QC					

^{*} Other options are available on request